

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant(s): Yasuo KOBAYASHI, et al.  
U.S. Serial No.: 10/585,994

**CONFIRMATION NO.: 8859**  
Group Art Unit: 2823

Filed: July 13, 2006

Examiner: Kevin A. Parendo

For: MANUFACTURING METHOD OF SEMICONDUCTOR DEVICE AND FILM  
DEPOSITION SYSTEM

**FOURTH INFORMATION DISCLOSURE STATEMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:


Pursuant to the duty of disclosure under 37 C.F.R. 1.56, Applicants are enclosing an Information Disclosure Citation Form (PTO-1449) which lists the references cited in a Japanese Office Action issued on October 6, 2009 for JP2005-006206. No copies of the U.S. documents cited therein are enclosed.

Applicants point out that they have **not** claimed priority from JP2005-006206 but they still consider it a "counterpart" to this U.S. application. Hence, they still certify under 37 C.F.R. 1.97(e)(1) that each item of information contained in this Information Disclosure Statement was first cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of the information disclosure statement. Hence, no fee is considered necessary with the Statement. If the Examiner does not agree with this an authorization is given to charge SGR Deposit Account No. 02-4300 of the underlying certification for the amount of \$180.00.

It is respectfully requested that the cited documents be considered by the Examiner, that they be made officially of record therein, and that the documents be listed on the face of any patent which may issue from this application.

Respectfully submitted,  
SMITH, GAMBRELL & RUSSELL, LLP

By:

  
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